



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re the Application of: **HATTORI, Kazuhiro**

Serial No.: **09/816,784**

Filed: **March 26, 2001**

Group Art Unit: 1765

Examiner: **Lan Vinh**

P.T.O. Confirmation No.: 5542

For: **DRY ETCHING METHOD, MICROFABRICATION PROCESS AND DRY ETCHING MASK**

**RESPONSE UNDER 37 CFR §1.116**

**- EXPEDITED RESPONSE -  
GROUP ART UNIT 1765**

**MAILSTOP AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

January 22, 2004

Sir:

In response to the Office Action dated **October 22, 2003**, please amend the above-identified application as follows:

RECEIVED  
JAN 26 2004  
TC 1700

AF  
OK to enter  
LV  
2/5/2004